Listing of Claims:

- 1. (original) A bipolar junction transistor, comprising:
 - a substrate;

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- a dielectric layer formed on the substrate;
- an opening formed in the dielectric layer to expose a portion of the substrate;
- a semiconductor layer formed on a sidewall and a bottom of the opening, the semiconductor layer extending outside the opening and above the dielectric layer;
- a spacer formed on the semiconductor layer to define a self-aligned emitter region in the opening;
- an emitter conductivity layer being filled into the self-aligned emitter region, and a PN junction being formed between the emitter conductivity layer and the semiconductor layer; and
 - a salicide layer formed on the emitter conductivity layer and on the portion of the semiconductor layer extending outside the opening and above the dielectric layer.
 - 2. (original) The bipolar junction transistor of claim 1, wherein the semiconductor layer comprises at least one material selected from a material group consisting of silicon epitaxy, GaAs, InP and AlGaAs.
- 3. (original) The bipolar junction transistor of claim 1, further comprising a selective implant collector region formed in the substrate beneath the semiconductor layer.
 - 4. (original) The bipolar junction transistor of claim 1, further comprising an extended conductivity layer formed on the dielectric layer to connect to the semiconductor layer.
 - 5. (original) The bipolar junction transistor of claim 4, further comprising an oxide layer and a silicon nitride layer formed between the extended conductivity layer and the dielectric layer.

- 6. (original) The bipolar junction transistor of claim 4, wherein the extended conductivity layer is composed of polysilicon.
- 5 7. (original) A hetero-junction bipolar junction transistor, comprising:
 - a substrate;

- a dielectric layer formed on the substrate;
- an opening formed in the dielectric layer to expose a portion of the substrate;
- a GaAs layer formed on a sidewall and a bottom of the opening;
- a spacer formed on the GaAs layer to define a self-aligned emitter region in the opening; and
 - an emitter conductivity layer being filled into the self-aligned emitter region, and a PN junction being formed between the emitter conductivity layer and the GaAs layer.
- 8. (original) The hetero-junction bipolar junction transistor of claim 7, further comprising a selective implant collector region formed in the substrate beneath the GaAs layer.
 - 9. (original) The hetero-junction bipolar junction transistor of claim 7, wherein the GaAs layer extends outside the opening and above the dielectric layer.
 - 10. (original) The hetero-junction bipolar junction transistor of claim 9, further comprising a salicide layer formed on the emitter conductivity layer and on the portion of the GaAs layer extending outside the opening and above the dielectric layer.
- 11. (original) The hetero-junction bipolar junction transistor of claim 7, further comprising an extended conductivity layer formed on the dielectric layer to connect to the GaAs layer.

- 12. (original) The hetero-junction bipolar junction transistor of claim 11, further comprising an oxide layer and a silicon nitride layer formed between the extended conductivity layer and the dielectric layer.
- 5 13. (original) The hetero-junction bipolar junction transistor of claim 11, wherein the extended conductivity layer is composed of polysilicon.
 - 14. (original) A hetero-junction bipolar junction transistor, comprising:
 - a substrate;

- a dielectric layer formed on the substrate;
 - an opening formed in the dielectric layer to expose a portion of the substrate;
 - a InP layer formed on a sidewall and a bottom of the opening;
 - a spacer formed on the InP layer to define a self-aligned emitter region in the opening; and
- an emitter conductivity layer being filled into the self-aligned emitter region, and a PN junction being formed between the emitter conductivity layer and the InP layer.
 - 15. (original) The hetero-junction bipolar junction transistor of claim 14, further comprising a selective implant collector region formed in the substrate beneath the InP layer.
 - 16. (original) The hetero-junction bipolar junction transistor of claim 14, wherein the InP layer extends outside the opening and above the dielectric layer.
- 17. (original) The hetero-junction bipolar junction transistor of claim 16, further comprising a salicide layer formed on the emitter conductivity layer and on the portion of the InP layer extending outside the opening and above the dielectric layer.

- 18. (original) The hetero-junction bipolar junction transistor of claim 14, further comprising an extended conductivity layer formed on the dielectric layer to connect to the InP layer.
- 19. (original) The hetero-junction bipolar junction transistor of claim 18, further comprising an oxide layer and a silicon nitride layer formed between the extended conductivity layer and the dielectric layer.
- 20. (original) The hetero-junction bipolar junction transistor of claim 18, wherein the extended conductivity layer is composed of polysilicon.
 - 21. (original) A hetero-junction bipolar junction transistor, comprising:
 - a substrate;

- a dielectric layer formed on the substrate;
- an opening formed in the dielectric layer to expose a portion of the substrate;
 - an AlGaAs layer formed on a sidewall and a bottom of the opening;
 - a spacer formed on the AlGaAs layer to define a self-aligned emitter region in the opening; and
- an emitter conductivity layer being filled into the self-aligned emitter region, and a PN junction being formed between the emitter conductivity layer and the AlGaAs layer.
 - 22. (original) The hetero-junction bipolar junction transistor of claim 21, further comprising a selective implant collector region formed in the substrate beneath the AlGaAs layer.
 - 23. (original) The hetero-junction bipolar junction transistor of claim 21, wherein the AlGaAs layer extends outside the opening and above the dielectric layer.

- 24. (original) The hetero-junction bipolar junction transistor of claim 23, further comprising a salicide layer formed on the emitter conductivity layer and on the portion of the AlGaAs layer extending outside the opening and above the dielectric layer.
- 5 25. (original) The hetero-junction bipolar junction transistor of claim 21, further comprising an extended conductivity layer formed on the dielectric layer to connect to the AlGaAs layer.
- 26. (original) The hetero-junction bipolar junction transistor of claim 25, further comprising an oxide layer and a silicon nitride layer formed between the extended conductivity layer and the dielectric layer.
 - 27. (original) The hetero-junction bipolar junction transistor of claim 25, wherein the extended conductivity layer is composed of polysilicon.